PTO/SB/08b (08-03) (AW 10/2003)

Approved for use through 6/30/2006, OMB 0651-0031

U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

Substitute for Form 1449B/PTO	C mpl te if Kn wn		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)	Application Number	10/628,549	
	Filing Date	July 28, 2003	
	First Named Inventor	N. Shimizu et al.	
	Art Unit	2832	
	Examiner Name		
SHEET 1 of 1	Attorney Docket No.	MAT-8448US	

NON-PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No.1	Include name of the author (In CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	Τ²	
916		S. Meninger et al. "Vibration-to-Electric Engery Conversion", Proceedings 1999 International Symposium on Low Power Electronics and Design, (ISLPED), Aug 16-17, 1999, pgs. 48-53.		
		M.A. Rosa et al. "Enhanced Electrostatic Force Generation Capability of Angled Comb Finger Design used in Electrostatic Comb-Drive Actuators", Electronics Letters, IEE Stevenage, GB, vol. 34, no. 18, September 3, 1998, pgs. 1787-1788.		
10		E. Ollier et al. "Integrated Electrostatic Micro-Switch for Optical Fibre Networks Driven by Low Voltage, Electronics Letters, IEE Stevenage, GB, vol. 32, no. 21, October 10, 1996, pgs. 2007-2009.		
Mas		European Search Report corresponding to application no. EP 03 01 6626 dated October 20, 2003.		
		24/10	0	
Examiner Signature	 	6) What Wiedhoff Date Considered 10/13/01		

considered. Include copy of this form with next communication to Applicant.

Applicant's unique citation designation number (optional).

Applicant is to place a check mark here if English language translation is attached.

The collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

PTO/SB/08B (AW 4/25/03) (04-03)
Approved for use through 04/30/2004, 0MB 0651-0031
U.S. Patent and Tradomark Office: U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

Complete If Known Substitute for Form 1449/PTO To Be Assigned Application Number INFORMATION DISCLOSURE July 28, 2003 Filing Date STATEMENT BY APPLICANT Norisato Shimizu First Named Inventor (Use as many sheets as necessary) Art Unit Examiner Name MAT-8448US Attorney Docket No. SHEET 1 of 1

Mary 12	100	NON-PATENT LITTERATURE, DOCUMENTS	4	
Examiner Initials	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T2	
Mon		H.A.C. TILMANS et al., "Wafer-level packaged RF-MEMS switches fabricated in a CMOS fab"		
Y/OV		IEEE 2001 IEDM Tech. Digest 01 921-924 (41.4.1-41.4.4)		
/		DOOYOUNG HAH et al., "A Low Voltage Actuated Microelectromechanical Switch for RF Application"		
0/1		JPN.J. Appl. Phys. Vol. 40(2001) pp. 2721-2724	 	
ONWY		OSAMU TUBOI et al., "A Rotational Comb-Driven Micromirror with a Large Deflection Angle and Low Drive Voltage" IEEE 1002 MEMS Tech. Digest, pp. 532-535		
	1.			
<u></u>				
<u> </u>				
			0	
	L		1	
Examiner	1/1	Date Considered A 13 65	•	

¹Applicant's unique citation designation number (optional).
²Applicant is to place a check mark here if English language translation is attached.

The collection of information is required by 37 CFR 1.98. The information is retained obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND T:

Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

^{*}EXAMINER: Initial If reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.